



Seiko Seiki STP-1003C

Technical Specifications

	STP1003	STP1003C	
Inlet flange size	ISO200F/ISO200K/DN200CF/ ISO250F/ISO205K		
Pumping speed N ₂ /H ₂	1000/800		Litres/second
Compression ratio N ₂ /H ₂	>10 ⁸ /10 ⁵		
Ultimate pressure			
ISO inlet flange	10 ⁻⁷ (10 ⁻⁹)	6.5 x 10 ⁻⁶ (5 x 10 ⁻⁸)	Pa (Torr)
CF inlet flange	10 ⁻⁸ (10 ⁻¹⁰)	10 ⁻⁷ (10 ⁻⁹)	Pa (Torr)
Maximum continuous outlet pressure*	13 (0.1)		Pa (Torr)
Maximum Nitrogen throughput**	130		sccm
Rated speed	35000		rpm
Start time	6		minutes
Maximum inlet flange temperature‡	120		°C
Power consumption (continuous)	800		VA
Input voltage	100 - 240		V
Weight, pump/controller	31/9		kg

* water cooled † C version ‡ with cooling



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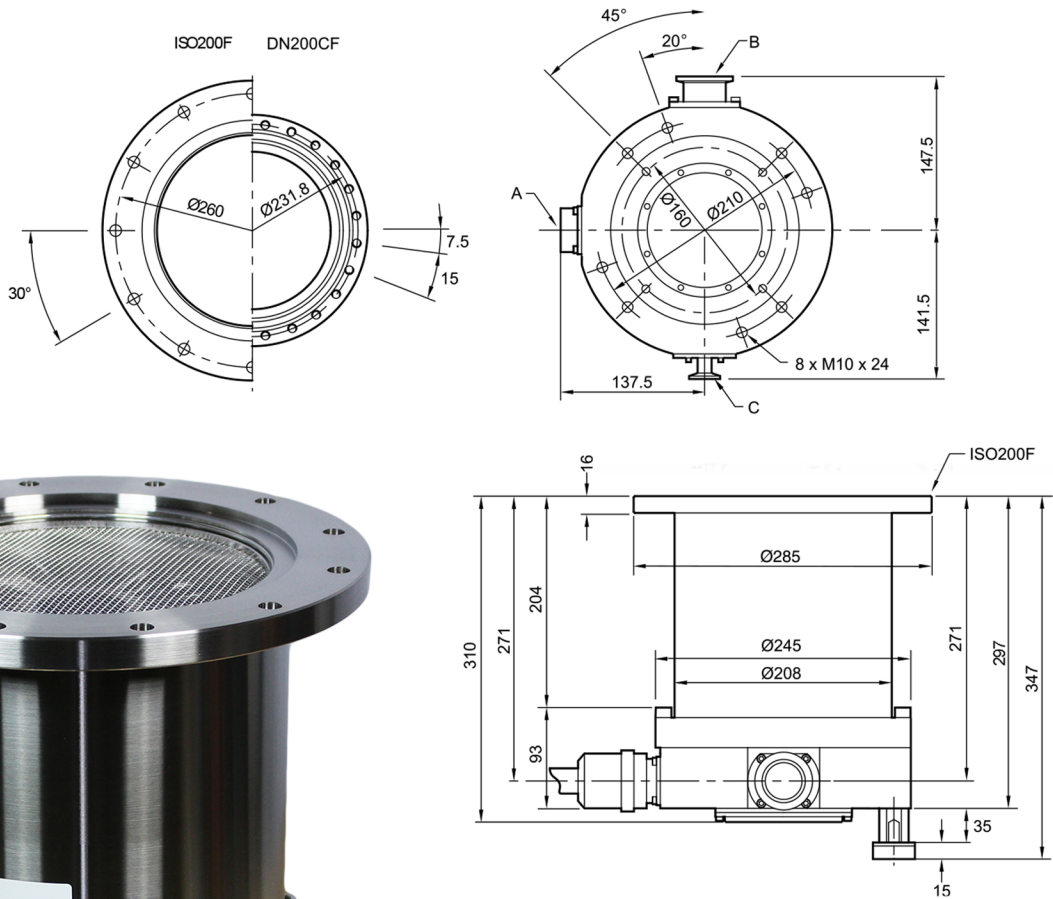
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Dimensions





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Features & Benefits

- oil free
- low vibration
- high reliability
- maintenance free
- harsh process compatible
- increased life
- advanced controller design
- compact design
- small footprint
- advanced rotor technology
- installation in any orientation

Applications

- plasma etch • ECR etch • film deposition • sputtering • ion implantation source • beam line pumping • MBE • diffusion • photo resist stripping
- crystal / epitaxial growth • wafer inspection • load lock chambers

Recommended controller/backing pump

- controllers: SCU-750 • SCU-800
- backing pumps: E2M28 • E2M30